



1765  
[10191/3964]

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s) : Franz LAERMER et al.  
Serial No. : 10/530,612  
Filed : December 30, 2005  
For : **PLASMA SYSTEM AND METHOD FOR  
ANISOTROPICALLY ETCHING STRUCTURES  
INTO A SUBSTRATE**

Art Unit : 1765  
Examiner : Maki A. Angadi  
Confirmation No. : 6739

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

Date: July 30, 2007

Reg. No. 31,792

Signature: \_\_\_\_\_

Richard M. Rosati

**AMENDMENT**

SIR:

In response to an April 5, 2007 Office Action in the above-identified application, please amend, without prejudice, the above-captioned application as follows. Applicants request a **one-month extension of time** to respond to the Office Action (extended periods expires on August 5, 2007), and the Office is authorized to charge the one-month extension fee of **\$120** to **Kenyon & Kenyon LLP's** Deposit Account No. **11-0600**.

**Amendments to the Claims** are reflected in the **Listing of Claims**, which begins on page 2 of this paper.

**Remarks** begin on page 6 of this paper.

08/02/2007 SSESHE1 00000010 110600 10530612

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